

**Amendments to the Claims:**

Please cancel Claims 1 – 22 and 27 – 35, and add Claims 36 – 40 as indicated in the following listing of claims, which replaces all prior versions, and listings of claims in the application.

**Listing of Claims:**

1. – 22. (Canceled).

23. (Original) A method for operating an optical switch, the method comprising:  
tilting a first end of a micromirror assembly towards a substrate by applying a first electrostatic force; and

thereafter, holding the micromirror assembly in a first tilted position with respect to the substrate with a second electrostatic force originating from a point laterally beyond an orthogonal projection of the micromirror assembly on the substrate.

24. (Original) The method recited in claim 23 further comprising:  
releasing the micromirror assembly from the first tilted position;  
thereafter, tilting a second end of the micromirror assembly towards the substrate by applying a third electrostatic force; and

thereafter, holding the micromirror assembly in a second tilted position with respect to the substrate with a fourth electrostatic force originating from a point laterally beyond the orthogonal projection of the micromirror assembly on the substrate.

25. (Original) The method recited in claim 24 further comprising:  
selecting the first tilted position from a plurality of possible first tilted positions by establishing a potential difference between the micromirror assembly and a first electrode used to establish the second electrostatic force; and

selecting the second tilted position from a plurality of possible second tilted positions by establishing a potential difference between the micromirror assembly and a second electrode used to establish the fourth electrostatic force.

26. (Original) The method recited in claim 23 further comprising selecting the first tilted position from a plurality of possible first tilted positions by establishing a potential difference between the micromirror assembly and a first electrode used to establish the second electrostatic force.

27. – 35. (Canceled).

36. (New) The method recited in claim 23 wherein the first electrostatic force originates at a point laterally within the orthogonal projection of the micromirror assembly on the substrate.

37. (New) The method recited in claim 24 wherein the third electrostatic force originates at a point laterally within the orthogonal projection of the micromirror assembly on the substrate.

38. (New) The method recited in claim 25 wherein the plurality of possible first tilted positions are defined by first angles with respect to the substrate that deviate increasingly from horizontal with an increase in the potential difference between the micromirror assembly and the first electrode.

39. (New) The method recited in claim 38 wherein the plurality of possible second tilted positions are defined by second angles with respect to the substrate that deviate increasingly from horizontal with an increase in the potential difference between the micromirror assembly and the second electrode.

40. (New) The method recited in claim 26 wherein the plurality of first tilted positions are defined by angles with respect to the substrate that deviate increasingly from horizontal with an increase in the potential difference between the micromirror assembly and the first electrode.